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Abstract: The electrical discharge machining (EDM) performance of silicon carbide (SiC) ceramics is investigated varying their electrical and thermal conductivities by introducing graphene-based fillers. SiC/graphene nanocomposites with different amounts and types of graphene are manufactured. As graphene flakes appear preferred oriented within the material, the nanocomposites are EDMed in orthogonal directions respecting the graphene basal plane. The addition of graphene nanoplatelets to SiC ceramics dramatically increases the material removal rate (MRR), as compared to monolithic SiC ceramics, allowing the machining of microparts with a fine dimensional precision. A relationship between the EDM response and the transport properties is established, with a strong and direct dependence of MRR with the electrical conductivity of the workpieces, i.e., with the graphene content; while an inverse dependence with the thermal conductivity is observed. The EDM testing orientation of the nanocomposites clearly influences the EDM performance for graphene contents below the electrical percolation threshold.

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1 **Exceptional micromachining performance of silicon carbide ceramics by**
2 **adding graphene nanoplatelets**
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19 **Abstract**
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23 ceramics is investigated varying their electrical and thermal conductivities by
24 introducing graphene-based fillers. SiC/graphene nanocomposites with different
25 amounts and types of graphene are manufactured. As graphene flakes appear preferred
26 oriented within the material, the nanocomposites are EDMed in orthogonal directions
27 respecting the graphene basal plane. The addition of graphene nanoplatelets to SiC
28 ceramics dramatically increases the material removal rate (MRR), as compared to
29 monolithic SiC ceramics, allowing the machining of microparts with a fine dimensional
30 precision. A relationship between the EDM response and the transport properties is
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32 conductivity of the workpieces, i.e., with the graphene content; while an inverse
33 dependence with the thermal conductivity is observed. The EDM testing orientation of
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2 below the electrical percolation threshold.
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8 **Keywords:** graphene; silicon carbide; ceramic matrix composites; machining;
9 microcomponents
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17 **1. Introduction**

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20 The development of silicon carbide (SiC) ceramic microcomponents to be used,
21 among others, as part of microturbines, microreactors, and microelectromechanical
22 systems or as catalytic micros supports is attracting a great interest mainly due to the
23 excellent thermal, tribological and mechanical performance at high temperature of these
24 ceramics, jointly with their good resistance to corrosive and harsh environments [1,2].
25 However, the machining of SiC complex microparts is a complicated task when using
26 diamond grinding wheels, the most common technique, due to the high hardness and
27 brittle nature of SiC, which leads to expensive and time consuming processes for getting
28 microcomponents with relatively low accuracy and surface finishing.
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42 Electrical discharge machining (EDM) arises as one of the most suitable
43 methods to overcome these difficulties, since the material removal is caused by
44 electrical discharges, and mechanical forces between the electrode and the workpiece
45 are not developed [3]. The main constraint for EDM is that a minimum electrical
46 conductivity (σ_e) of the workpiece is required ($> 0.3-1.0 \text{ S}\cdot\text{m}^{-1}$) to enable the electrical
47 discharges [4], which can be a clear limitation in the machining process of SiC ceramics
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1 typically exhibiting lower conductivity values than those needed. Different approaches
2 have been considered to enhance the discharge efficiency of ceramics. In this way,
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4 Fukuzawa et al. [5] proposed the use of an assisting electrode method (AEM) to
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6 machine insulator ceramics by coating the workpiece with a conductive layer. This layer
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8 promotes the first discharges between the electrode and the workpiece. The pyrolytic
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10 carbon generated during the decomposition of the oil-based dielectric fluid adheres to
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12 the ceramic surface, leading to the continuous formation of an intrinsic conductive layer
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14 on the workpiece that allows the EDM process. Although AEM has successfully been
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16 employed for non-conductive SiC ceramics [6,7], the material removal rate was low and
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18 the electrode wear rate was quite high. Another approach to promote the EDM of low
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20 electrical conductive materials consisted in the addition of conductive powders into the
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22 dielectric fluid, known as powder mixed EDM (PMEDM) process [8]. Liew et al. [9]
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24 improved the electrical discharge frequency and the EDM performance of reaction
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26 bonded-SiC (RB-SiC) ceramics by incorporating electrical conductor carbon nanofibers
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28 to the dielectric fluid. Finally, successful EDM attempts were carried out in electrically
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30 conducting SiC materials. This is the case of the previously mentioned RB-SiC
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32 ceramics [10], where the silicon remained after the infiltration process slightly increased
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34 σ_e up to $\sim 10 \text{ S}\cdot\text{m}^{-1}$, or more noticeably by adding yttrium nitrate as sintering additive
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36 into SiC matrix to achieve σ_e values of $\sim 10^4 \text{ S}\cdot\text{m}^{-1}$ that allowed the EDM of quite
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38 complex SiC shapes [11].
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49 During the last years, graphene, in the form of graphene nanoplatelets (GNPs) or
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51 graphene oxide (GO) sheets, has become an extraordinary filler to enhance the electrical
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53 response of low conductor ceramics such as Al_2O_3 [12], ZrO_2 [13], Si_3N_4 [14] or B_4C
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55 [15]. Some of the present authors were also able to increase the electrical conductivity
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1 of SiC ceramics in three orders of magnitude by introducing GNPs [16], which, at the
2 same time, extraordinarily improved the tribological [17] and mechanical [18] responses
3 of these materials. Therefore, ceramic/graphene composites could be promising
4 materials to be EDMed, augmenting the machining efficiency as well. In this way, few
5 works have recently reported a better EDM performance of Si₃N₄ [19], B₄C [15], and
6 Al₂O₃ [20] by introducing GNPs fillers into the ceramic matrices. However, to the best
7 of our knowledge, EDM has not been employed to manufacture SiC/graphene parts
8 hitherto.
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20 In the present work, EDM tests were carried out in three different SiC monoliths
21 and two SiC/GNPs nanocomposites with distinct GNPs contents. All these materials
22 scanned a wide range of properties, especially in terms of the electrical and thermal
23 conductivities, aiming to establish a relationship between the EDM response and the
24 transport properties. Besides, the machining experiments were conducted varying the
25 energy conditions, and the graphene-based nanocomposites were tested on orthogonal
26 surfaces according to their anisotropic microstructure.
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40 **2. Experimental procedure**

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43 *2.1. Materials fabrication.* Five different SiC-based materials were chosen to explore
44 their EDM performances (Table 1), in particular, three monolithic SiC ceramics
45 showing distinct properties and two SiC/GNPs nanocomposites containing 10 and 20
46 vol.% of GNPs. Specimens of one of the monolithic SiC ceramics were commercially
47 manufactured (CD110 grade, CeramTec, Germany); whereas for the rest of
48 compositions fully dense specimens were produced in-house according to the
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1 experimental procedure described elsewhere [16,21]. In brief, SiC/GNPs powders were
2 processed by mixing and sonicating two isopropyl alcohol suspensions independently
3 prepared: one containing commercial GNPs (type N006, Angstrom Materials Inc., USA)
4 that were dispersed through a sonication process; and another SiC-based suspension
5 consisting on the attrition milled ceramic powder composition - 93 wt.% of micro-sized
6 β -SiC (BF-17A, H.C. Starck, Germany), 5 wt.% of Y_2O_3 (Grade C,H.C. Starck,
7 Germany), and 2 wt.% of Al_2O_3 (SM8, Baikowski Chimie, France). The dried and
8 sieved SiC/GNPs powder mixtures (labelled as 10GNPs and 20GNPs for 10 and 20
9 vol.% GNPs contents, respectively) were then spark plasma sintered (SPS, Dr. Sinter,
10 SPS-510CE, Japan) into disc specimens of 20 mm \times 3 mm at 1800 °C for 5 min,
11 applying a uniaxial pressure of 50 MPa during the heating cycle, and using a vacuum
12 atmosphere of \sim 6 Pa. Monolithic SiC specimens (0 vol.% GNPs) were equally
13 processed from the ceramic powders. Micro-sized and nano-sized β -SiC (NanoAmor,
14 USA) were employed as SiC raw powder into the monolithic ceramic composition.
15 Accordingly, the manufactured monolithic SiC specimens were labelled as μ -SiC and n-
16 SiC, respectively; meanwhile the commercial one was identified as C-SiC. Table 1
17 collects the different materials and their main properties.

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45 Table 1. Materials selected for EDM tests and their main morphological characteristics
46 and properties [16,18,21,22]: mean particle size (d_{50}), flexural strength (σ_f), fracture
47 toughness (K_{IC}), electrical conductivity (σ_e), and thermal conductivity (k_T). Transport
48 data (σ_e and k_T) in the parallel (\parallel) and perpendicular (\perp) directions to the SPS pressing
49 axis are also included for some materials. [†]Data reported by the supplier. * K_{IC} value

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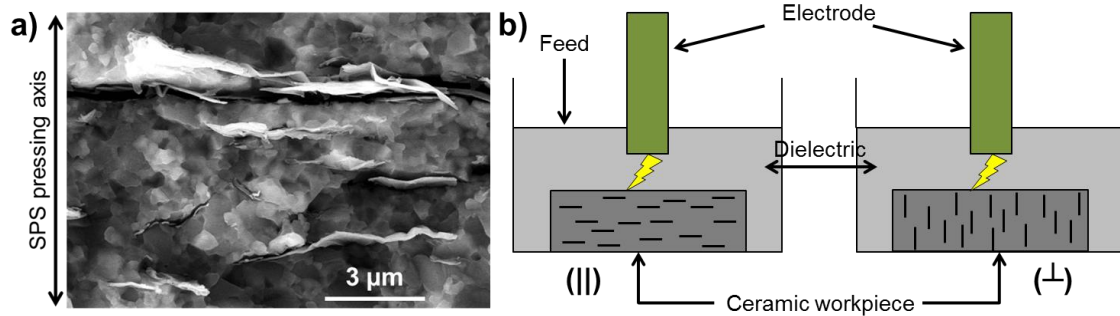
estimated by Vickers indentations at 49 N. For the rest of materials K_{IC} was assessed by the surface crack in flexure method.

Material	Label	d_{50} (μm)	σ_f (MPa)	K_{IC} (MPa $\text{m}^{1/2}$)	σ_e ($\text{S}\cdot\text{m}^{-1}$)	k_T ($\text{W}\cdot\text{m}^{-1}\cdot\text{K}^{-1}$)
Commercial monolithic SiC	C-SiC	3-5 [†]	440 [†]	3.8 [†]	2×10^{-6} [†]	100 [†]
Monolithic Nano SiC	n-SiC	0.4	---	3.5*	~33	29 () 67 (\perp)
Monolithic Micro SiC	μ -SiC	0.6	373	3.2	1 () 5 (\perp)	43 () 65 (\perp)
Micro SiC/10 vol.%GNPs	10GNPs	0.6	602	5.9	158 () 922 (\perp)	33 () 73 (\perp)
Micro SiC/20 vol.%GNPs	20GNPs	0.7	401	4.1	919 () 4380 (\perp)	25 () 84 (\perp)

It is important to remark that μ -SiC and n-SiC ceramics contained ~3-4 vol.% of graphene multilayers, which were in-situ grown at the SiC grain boundaries during the SPS process [21]. Besides, both types of graphene fillers, the in-situ grown and the added GNPs, appeared into the material preferentially oriented with their basal (ab)

1 plane perpendicular to the SPS pressing axis [16] (see an example in Figure 1a), leading
2 to materials with anisotropic properties (Table 1).
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5 2.2. *EDM tests.* The EDM trials were performed using a SARIX micro-EDM machine
6 (Model SX-200-HPM, Switzerland). In the case of n-SiC ceramics and 10GNPs and
7 20GNPs nanocomposites, their σ_e values (Table 1) were well above the limit ($\geq 1 \text{ S}\cdot\text{m}^{-1}$)
8 for directly using the EDM process. However, for the low electrical conducting C-SiC
9 and μ -SiC monolithic ceramics, it was not possible to employ EDM and AEM was
10 required to enable the machining process. In this way, C-SiC and μ -SiC specimens were
11 coated by screen printing with a conductive carbon lacquer layer of $\sim 25 \mu\text{m}$ of
12 thickness.
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Figure 1. a) SEM micrograph of the fracture surface of 10GNPs composite showing the preferential orientation of the GNPs with their basal plane perpendicular to the SPS pressing axis. b) Scheme of the EDM tests performed on the parallel (||) and perpendicular (\perp) directions of the materials with respect to the SPS pressing axis.

To explore the EDM performance of the ceramics and nanocomposites, three different EDM energy conditions were selected (Table 2) from preliminary trials that enabled a stable EDM process in all materials. In particular, the selected energy settings

1 corresponded to conventional fine machining (EDM-F) and rough and fast machining
2 (EDM-R1 and EDM-R2) processes. In the case of EDM-R1 and EDM-R2, the generator
3 only allows one discharge per pulse width, while for EDM-F a larger number of
4 discharges having shorter on times takes place. The main difference between rough
5 conditions is that the applied voltage is higher for EDM-R2 (Table 2). A tungsten
6 carbide rod with a diameter of 300 μm was used as tool electrode and microgrooves
7 were machined into the materials with the rotating microrods. The tests were carried out
8 using a machining depth and length of 50 μm and 200 μm , respectively, and an infeed
9 of 10 μm . IME 110 (Oelheld GmbH, Germany) was used as dielectric fluid. All the
10 materials were EDMed in the (\parallel) direction (Fig. 1b). In addition, EDM tests were also
11 carried out in the (\perp) direction (Fig. 1b) for the materials presenting a clear anisotropy
12 on their electrical and thermal conductivities (Table 2).

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The material removal rate (MRR) was calculated using the process time and the removed volume optically measured with a coordinate measuring machine (Werth Videocheck HA400, Germany). The surface roughness (S_q) of the machined surface was optically measured with a white light interferometer (Zygo, USA). The electrode tool wear ratio (EWR) was assessed from the ratio between the electrode wear volume and the removed workpiece volume. The analysis of the machined surfaces was done by scanning electron microscopy (SEM, DSM 962, Zeiss, Germany) and micro-Raman spectroscopy (Alpha300 WITec GmbH, Germany) using the 532 nm laser wave-length excitation. Raman maps of 25×25 pixels, recording one spectrum per pixel and using 1 s of acquisition time, were acquired on $50 \times 50 \mu\text{m}^2$ scanned areas. The micro hardness (H) of some of the materials was determined on the unmachined and EDMed surfaces at room-temperature (MHT-10, Anton Paar-Paar Physica, USA) using a diamond indenter

1 and an indentation force of 2.9 N. At least 10 indentation tests were carried out per
2 material.
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8 Table 2. Parameters of the different fine (EDM-F) and rough (EDM-R) machining
9 conditions.
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11 12 13 14 15 16 17 18 19 20 21 22 23 24 25 26 27 28	Energy conditions	Voltage (V)	Current (index)	Frequency (kHz)	Pulse width (μ s)
29	EDM-F	200	1	100	1
30	EDM-R1	140	25	100	1
31	EDM-R2	200	25	100	1

32 3. Results and discussion

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35 The EDM performance of the different tested materials, machined in the (||)
36 direction, versus the energy conditions is collected in Figure 2. At first glance, the
37 addition of GNPs to SiC ceramics dramatically increased the MRR (Fig. 2a), ranging,
38 for EDM-F testing condition, from $0.37 \times 10^{-2} \text{ mm}^3 \cdot \text{min}^{-1}$ (C-SiC) to 1.05×10^{-2}
39 $\text{mm}^3 \cdot \text{min}^{-1}$ (20GNPs), which represents an augment in MRR of ~186%. This
40 outstanding increment could be explained by the electrical and thermal properties of the
41 EDMed materials. As it is shown in Table 1, σ_e considerably augments in the (||)
42 direction while k_T moderately decreases, both when compared with monolithics having
43 similar matrices characteristics. In general, a high electrical conducting workpiece
44 would enlarge the probability for producing successful discharges during the EDM
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process, increasing the material removal. Actually, Figure 3a shows a strong and direct increasing dependence of MRR with σ_e (for values above $1 \text{ S}\cdot\text{m}^{-1}$), i.e., with the GNPs content in the case of the nanocomposites. In addition, comparing the MRR response of the different monolithic SiC, the best performance was attained for n-SiC ceramics, which exhibits the highest electrical conductivity (Table 1) due to both the graphene-like network formed in-situ and the strong doping during its sintering [21,23].

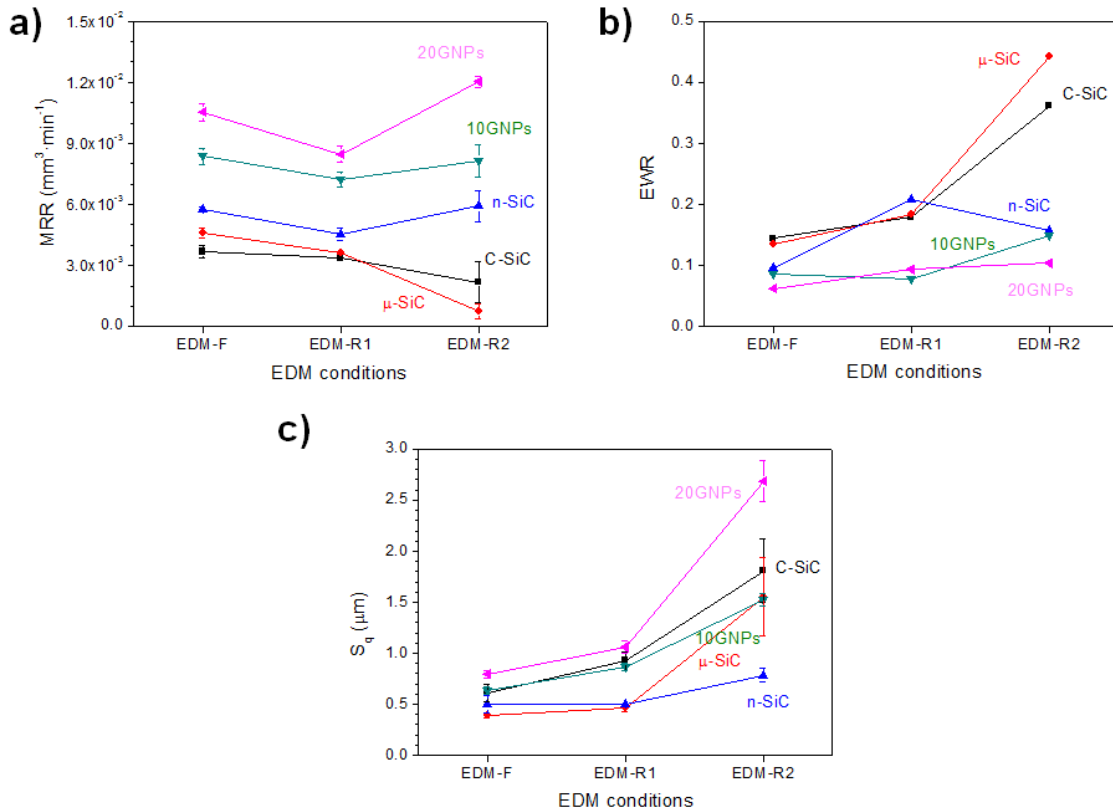
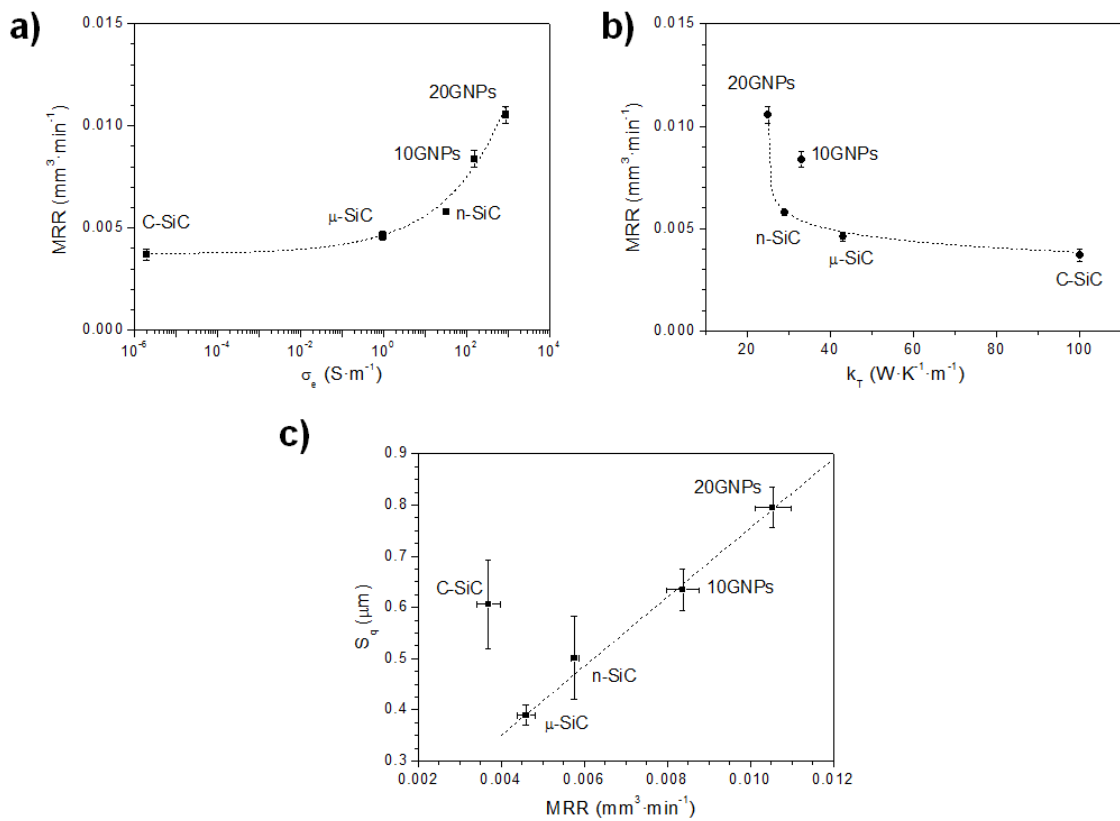


Figure 2. a) Material removal rate (MRR), b) electrode wear rate (EWR), and c) surface roughness (S_q) as a function of the EDM conditions for the different ceramic materials machined in the (||) configuration.

1 The thermal conductivity of the workpiece also influences the EDM process by
 2 affecting the dissipation of the generated heat and the material removal by thermal
 3 spalling. In this way, MRR data exhibited an inverse dependence with k_T (Fig. 3b).
 4 Besides, as k_T decreases (GNPs nanocomposites), heat losses diminish and the energy
 5 process is much focused to melt the workpiece, improving the EDM performance.
 6 Therefore, the better machining response of GNPs nanocomposites is explained by the
 7 combined effect of an increasing electrical conductivity and decreasing thermal
 8 conductivity.
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49 Figure 3. a) Material removal rate (MRR) at EDM-F as a function of the electrical and
 50 b) thermal conductivities of the EDMed materials in the (||) configuration. (c) Surface
 51 roughness (S_q) evolution versus material removal rate (MRR) using EDM-F settings and
 52 (||) configuration.
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3 At a first glance, the effect of the machining energy parameters on MRR does
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5 not follow a clear trend (Fig. 2a). Initially, larger MRR values should be expected for
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7 rough machining EDM-R1 and EDM-R2 settings. This is not the case for EDM-R1,
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9 where MRR decreased for all the materials probably due to both the lower spark voltage
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11 and the limitation of one discharge per pulse width, in comparison with higher voltage
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13 and the larger number of discharges for EDM-F. Despite the discharges limitation of
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15 EDM-R2, its higher voltage augmented MRR for the materials machined using EDM
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17 (n-SiC, 10GNPs, 20GNPs) up to similar or even higher values than those attained for
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19 EDM-F. However, when AEM testing C-SiC and μ -SiC materials, MRR further
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21 decreased due to the excessive generation of pyrolytic carbon which was not sufficiently
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23 flushed away, causing instabilities in the machining process.
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30 EWR for all the materials is plotted as a function of the machining conditions in
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32 Fig. 2b. The results evidence that, independently of the EDM conditions, GNPs
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34 nanocomposites led to lower EWR values (< 0.15), which is a clear indicator of their
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36 finer dimensional precision and better EDM performance. In particular, 20GNPs
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38 nanocomposite reached at EDM-F an EWR value of up to 132% and 55% lower than
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40 monolithic SiC ceramics machined with and without AEM, respectively. Besides, a
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42 larger GNPs content provided a better EWR response (37% at EDM-F for 20 vol.% of
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44 GNPs). In general, EWR significantly augmented for non-conducting materials as the
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46 energy parameters increased, reaching values above 0.4.
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52 The surface analysis by SEM of the machined workpieces (Figure 4) evidenced
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54 the formation of either discharge craters in the case of AEMed materials (C-SiC and μ -
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SiC, Figs. 4a,c) or a recast layer over the machined surface for the rest of conducting materials (n-SiC and GNPs nanocomposites, Figs. 4b,d,e), the latter confirming a removal mechanism by melting process of the liquid-phase sintered materials.

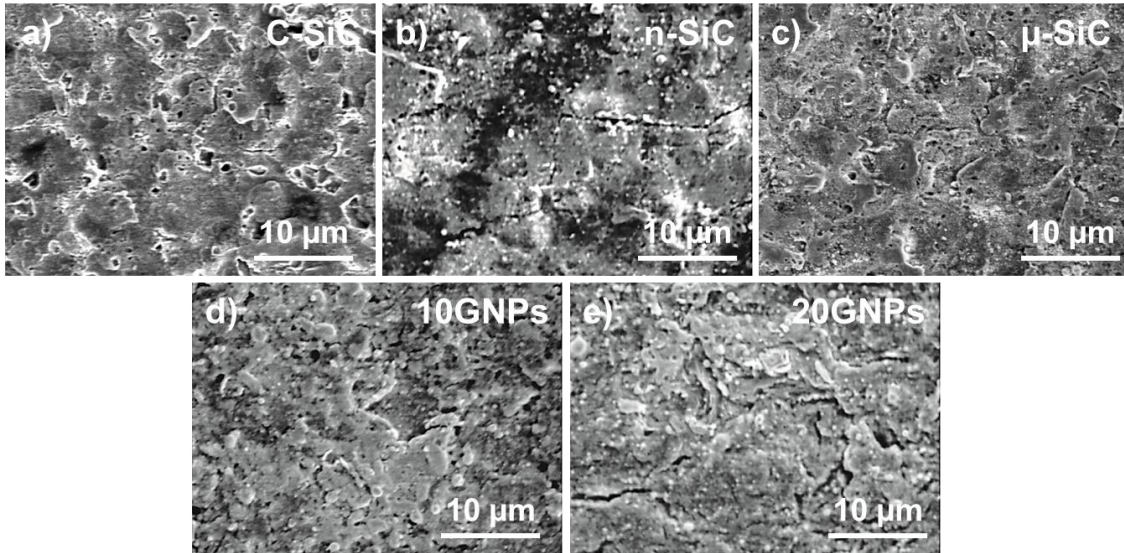


Figure 4. SEM micrographs of the EDMed surfaces at EDM-F in the (||) configuration for: a) C-SiC, b) n-SiC, c) μ-SiC, d) 10GNPs, and e) 20GNPs materials.

An important issue in the EDM process is the surface roughness of the machined workpieces, which must be low enough to avoid further polishing treatments that would raise the final production costs. As expected, the fine machining setting conditions (EDM-F) produced S_q values below 1 μm for all materials (Fig. 2c); whereas S_q increased for rough machining conditions, especially for EDM-R2 (up to 2.7 μm for 20GNPs nanocomposite), where an increase of the energy input into the surface occurred. In addition, when plotting S_q versus MRR at EDM-F, a clear relationship was observed (Fig. 3c). In this way, the roughness of the machined workpieces linearly augmented with the MRR except for C-SiC. The unexpected high S_q attained for this

1 ceramic material considering its relatively low MRR could be explained by its large
2 grain size (3-5 μm), almost one order of magnitude bigger than for the rest of materials
3 (Table 1), that would produce deeper craters and, hence, higher S_q . In view of EDM-F
4 led to the best EDM performance of the tested materials in terms of high MMR, and low
5 EWR and S_q , this energy parameter was selected for the following studies.
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13 Micro-Raman spectroscopy can also be used as tool to analyse the surface
14 damage of the EDMed surfaces. In this way, n-SiC ceramics and 10GNPs and 20GNPs
15 nanocomposites, chosen by their better EDM performance, were characterized by
16 Raman spectroscopy (Figure 5). The unmachined surfaces (Fig. 5a) of the GNPs
17 nanocomposites exhibited Raman peaks centred at $\sim 805\text{ cm}^{-1}$ and $\sim 975\text{ cm}^{-1}$,
18 corresponding to the transverse-optical (TO) and longitudinal optical (LO) modes of β -
19 SiC [24], respectively, and the three characteristic bands of graphitic species associated
20 to GNPs [25], i.e., D- ($\sim 1360\text{ cm}^{-1}$), G- ($\sim 1595\text{ cm}^{-1}$), and 2D-bands ($\sim 2717\text{ cm}^{-1}$). The
21 n-SiC ceramics also present these bands, although less intense, due to the in-situ growth
22 of a graphene network during the ceramic densification by SPS [21], and only the SiC-
23 TO band at $\sim 805\text{ cm}^{-1}$ is observed for this material reflecting its high doping level [23].
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0.95 to 1.37 for n-SiC, 0.26 to 1.22 for 10GNPs, and 0.36 to 0.92 for 20GNPs. These results mean that graphene flakes on the machined surface became highly damaged after the severe testing conditions used for EDM.

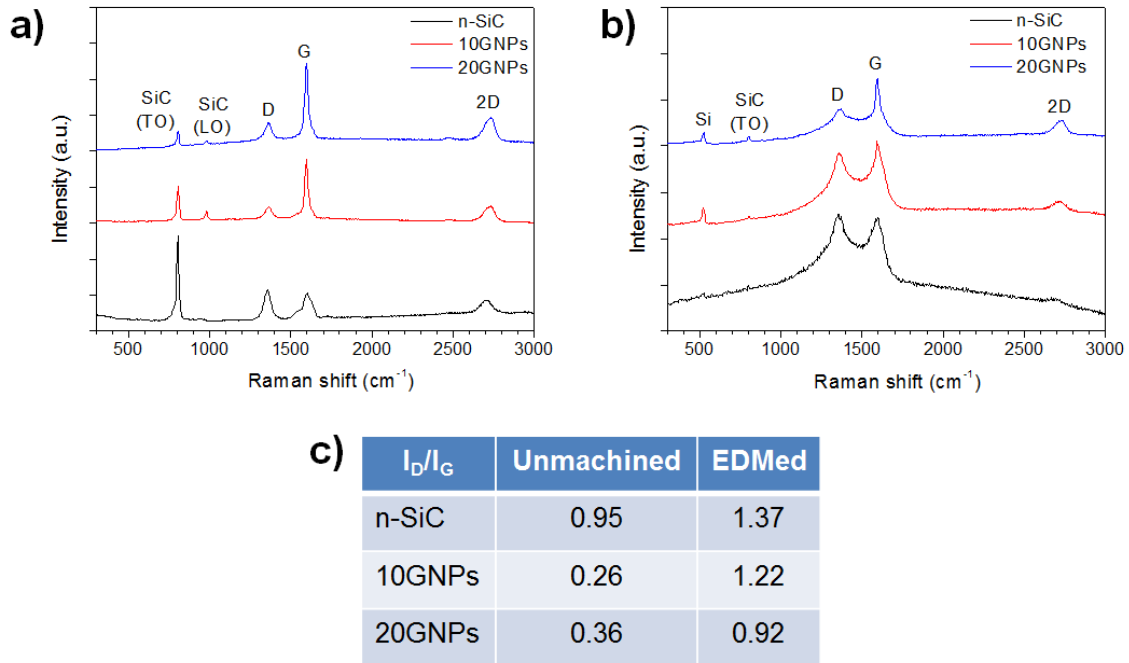
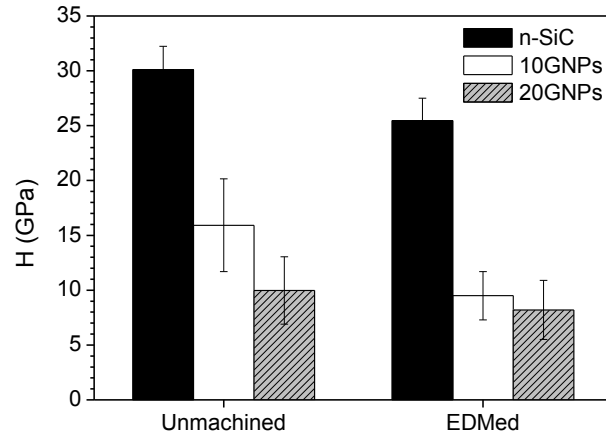


Figure 5. Average Raman spectra of the n-SiC ceramics and 10GNPs and 20GNPs nanocomposites before (a) and after (b) EDM tests performed at EDM-F in the (||) configuration. c) Table summarizing the Raman I_D/I_G values for the unmachined and EDMed surfaces.

As it was previously reported by some of the authors [17], the addition of GNPs to SiC decreased the hardness due to the sliding phenomenon of the graphene layers within the nanoplatelets. After EDM, the surface damage of the machined workpiece, evidenced by the decomposition of SiC, and in the case of nanocomposites by the GNPs degradation as well, led to the reduction of the hardness. After EDM process, H values

1 for both nanocomposites were very similar, which means that hardness is controlled by
2 the recast layer.
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25 Figure 6. Hardness (H) tested in the (||) direction for the unmachined and EDMed
26 (EDM-F) surfaces for n-SiC, 10GNPs, and 20GNPs materials.
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33 As a proof of concept of the excellent EDM performance attained for GNPs
34 nanocomposites in absence of the AEM, different high quality micropillars and
35 microholes were machined (Figure 7). The EDMed structures showed in all cases very
36 sharp and defined edges with no sign of damage, proving the benefits of adding
37 graphene fillers to low electrically conducting ceramics for EDM microfeatures with
38 high structural stability.
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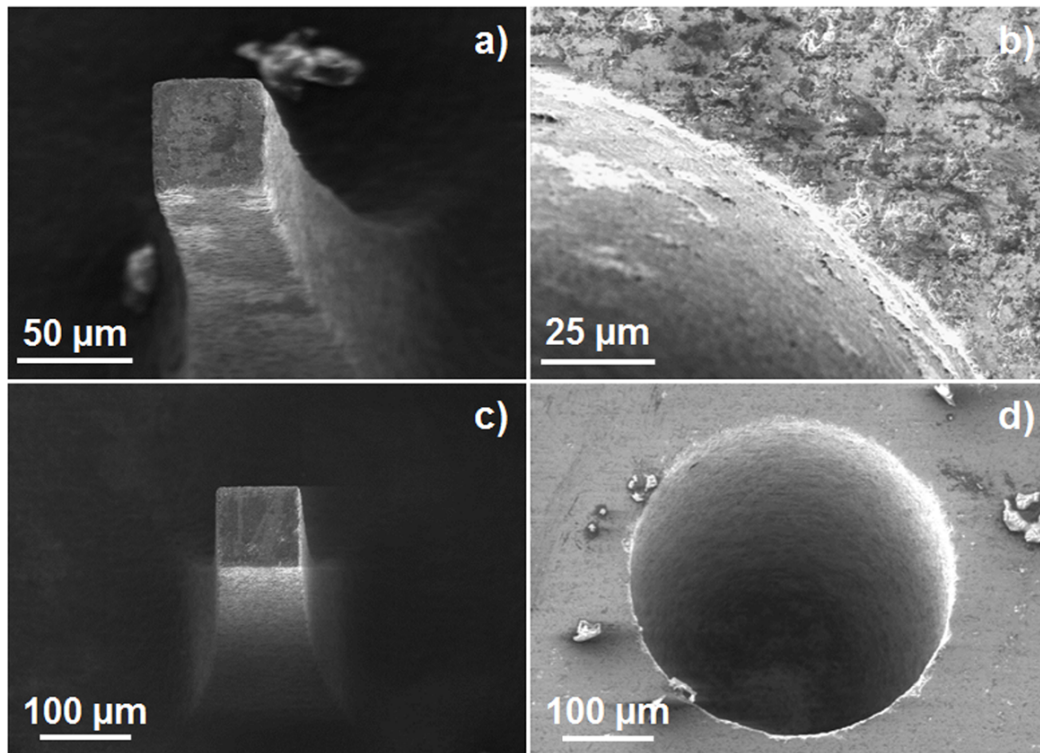


Figure 7. SEM micrographs showing some examples of EDMed features (micropillar and microhole) in the 10GNPs (a,b) and 20GNPs nanocomposites (c,d). High magnification SEM image in b) shows the edge of a microhole.

The EDM performance in the (\perp) configuration for n-SiC ceramics and GNPs nanocomposites is depicted in Figure 8, where the fine machining conditions (EDM-F) seem to get the best MRR response (Fig. 8a). Interestingly, when comparing MRR for both testing directions at EDM-F (Fig. 8b), similar results were attained except for the 10GNPs nanocomposite, where a 35% increase was achieved in the (\perp) direction (MRR $\sim 1.1 \times 10^{-2} \text{ mm}^3 \cdot \text{min}^{-1}$) as compared to data assessed in the (\parallel) one. This behaviour is explained considering the relationship between the electrical properties and the MRR (Fig. 8c). Actually, 10GNPs shows complete connectivity between the nanoplatelets in

the (\perp) orientation ($\sigma_e = 922 \text{ S}\cdot\text{m}^{-1}$) but not in the (\parallel) one ($\sigma_e = 158 \text{ S}\cdot\text{m}^{-1}$). Therefore, an increase in σ_e promoted more efficient electrical discharge and removal mechanisms until the electrical percolation threshold was reached, where the maximum efficiency of the EDM occurred (Fig. 8c). A further increment in σ_e above $\sim 900 \text{ S}\cdot\text{m}^{-1}$ had a negligible effect in MRR.

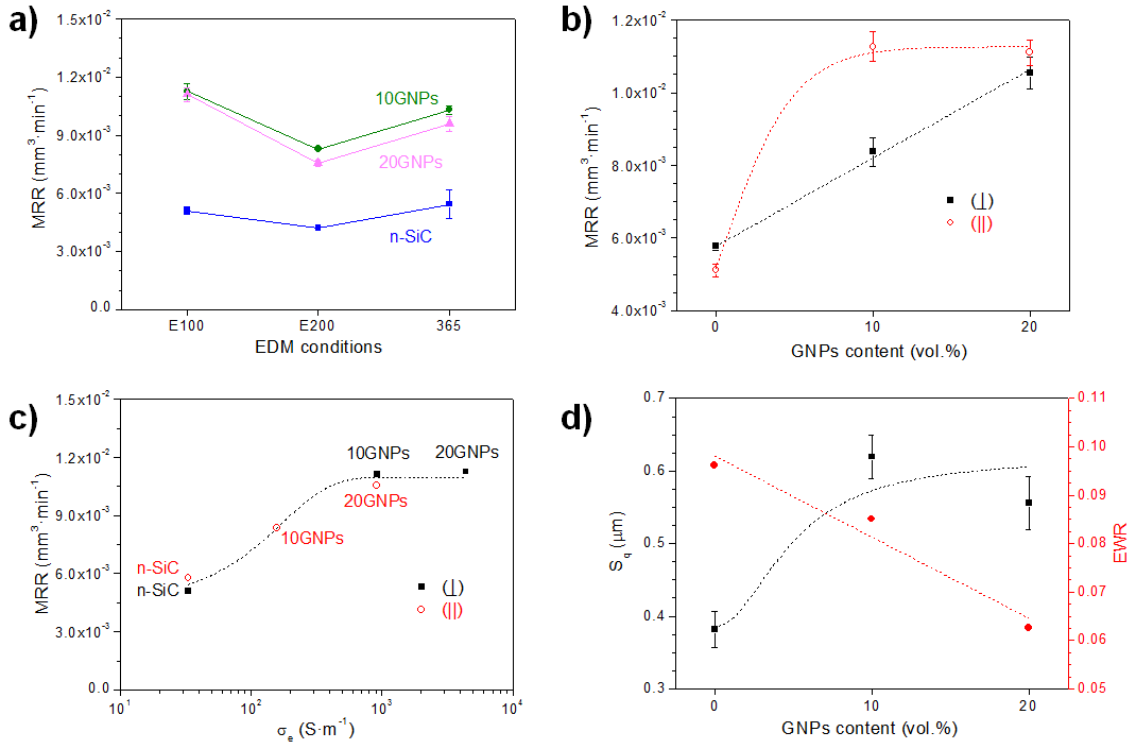
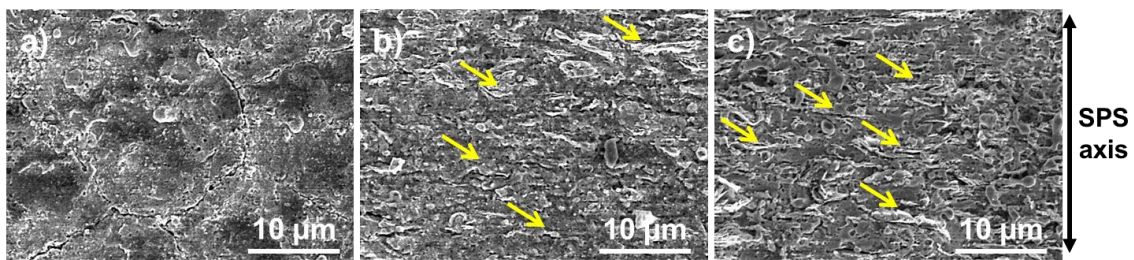


Figure 8. EDM performance of n-SiC ceramics and 10GNPs and 20GNPs nanocomposites tested in the (\perp) configuration. a) Material removal rate (MRR) versus EDM conditions, b) MRR as a function of the GNPs content for the (\perp) and (\parallel) directions at EDM-F, c) relationship between the electrical (σ_e) conductivity and the MRR response using EDM-F settings for both testing directions, and d) surface roughness (S_q) and electrode wear rate (EWR) versus GNPs content at EDM-F in the (\perp) configuration.

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3 As it was also observed for the (\parallel) orientation, S_q scaled with MRR showing a
4 similar trend (Fig. 8d), although the surface finishing kept quite smooth ($< 0.7 \mu\text{m}$) for
5 all materials. Finally, the clear benefits of adding GNPs into EWR are shown in Fig. 8d,
6 where an almost linear improvement of the dimensional precision (lower EWR) with
7 the GNPs content was evidenced.
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12 The SEM observations of the surfaces EDMed in the (\perp) direction showed the
13 formation of a recast layer (Figure 9), as occurred for the (\parallel) surfaces. GNPs
14 perpendicularly oriented to the SPS pressing axis were perceived for this orientation
15 (pointed by arrows in Figs. 9b,c).
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37 Figure 9. SEM micrographs of the EDMed surfaces at EDM-F in the (\perp) configuration
38 for: a) n-SiC, b) 10GNPs, and c) 20GNPs materials. The arrows in (b) and (c) point the
39 GNPs.
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48 It can be concluded that the testing orientation has a limited influence in the
49 EDM performance of materials with low (n-SiC) and high (20GNPs) amounts of GNPs,
50 but it is extremely important for intermediate contents (10GNPs), the EDM response
51 being much better for the (\perp) direction and closer to that of 20GNPs.
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3 **Conclusions**
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6 The EDM performance of SiC ceramics is clearly enhanced by adding graphene fillers
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8 to the ceramic matrix, allowing to machine microfeatures with high level of accuracy
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10 and surface roughness below 1 μm . A relationship between this outstanding EDM
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12 response of SiC/GNPs nanocomposites and the transport properties is established,
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14 showing a strong and direct dependence of MRR with the electrical conductivity of all
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16 materials. The nanocomposite with the highest GNPs content (20 vol.%) exhibits, as
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18 compared to monolithic SiC ceramics, an increment on MRR of up to 186% jointly with
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20 a reduction on EWR of up to 132%. The machining orientation affects the EDM
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22 performance of GNPs nanocomposites for intermediate contents where the electrical
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24 percolation is attained only in the direction perpendicular to the SPS pressing axis. The
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26 employ of EDM on SiC/graphene materials opens new opportunities for manufacturing
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28 complex SiC-based microcomponents to be used, among others, in the electronic and
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30 energy fields.
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41 **Acknowledgements**
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46 MAT2015-67437-R projects).
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